Next-Level Nanotechnology Tools 🚦 swiss quality

# Alphacen 300

# The tip-scanning AFM for heavy & large samples up to 300 mm







# Alphacen 300 mm: The tip-scanning AFM for large and heavy samples

Nanosurf is the market leader for custom developed systems for large and heavy samples. Over the past years our team has built a substantial knowledge base developing these custom stages for various customers.

Utilizing this vast body of knowledge, we have now developed a standard product for large samples up to 300 mm or heavy samples up to 45 kg. The Alphacen 300 reduces the price and the delivery time compared to a custom system.

## Handle heavy samples with ease thanks to tip scanning and air bearings

Heavy samples demand special handling: the Alphacen 300 can move samples up to 45 kg virtually frictionless with a repositioning accuracy of 2 µm thanks to the employed air bearings. The sample stage is lifted up using pressurized air or nitrogen, and high-precision belts move it as required. Once the area of interest on the sample is reached, the air pressure is released, putting the sample in position for measurement without stage drift. For scanning Alphacen 300 uses tip-scanning technology, keeping the size and weight of the moving parts at a minimum.

### Run automated measurement series

The Alphacen 300 includes powerful automation software that allows the user to preselect the locations of interest, either on an optical image or a stage map, and let the system collect the images with no user intervention. Set up a measurement series on your sample (or multiple samples) and safely let the system do the rest.

# Large samples

The Alphacen 300 AFM system has a sample stage that can move 300 mm x 300 mm in XY and can measure every point on a 300 mm sample. On request, the stage can be modified semiconductor wafers. However, one of the limitations of to handle a larger range in X (up to 500 mm).

The XY stage has a resolution of 1 µm and a positioning accuracy of 2 µm which allows for precise positioning of the sample under the imaging tip.

The software's integrated automation feature enables time saving pre-programming of measurement series.

# Heavy glass samples

Most large sample AFMs are capable of handling planar samples up to 200 mm, typically geared toward analysis of these systems is the sample weight that they can handle.

Alphacen 300 addresses the need for a standard AFM capable of imaging large and heavy samples with a weight limit of up to 45 kg. The Z-stage travel of 50 mm also allows for imaging of samples that are not thin silicon wafers.

Large, heavy samples are quite commonplace in the optical industry, e.g. in the production of large lenses and semiconductor industry, e.g. assembled cassettes or completed products.



#### SiC steps

Scan size: 1.5 μm x 1.5 μm The scan shows the

step heights of 0.75 nm between each terrace.



Glass

Scan size:

5 µm x 5 µm Surface roughness: 0.112nm RMS

(0.087nm Ra)

# System functionality

| Standard imaging<br>modes      | Static force, dynamic force, phase contrast,<br>MFM, friction force, force modulation, spreading<br>resistance, EFM              |
|--------------------------------|--|
| Imaging functions              | Up to 8000×8000 data points<br>X/Y sample slope correction   |
| Standard<br>spectroscopy modes | Force–distance, amplitude–distance, phase–<br>distance, tip current–tip voltage  |
| Spectroscopy<br>functions      | Setup wizard for each spectroscopy mode<br>XY-position table: point, line, and grid  |
| Standard<br>lithography modes  | Free vector objects drawing or real-time<br>drawing by mouse<br>Tip lift or force control during movement from<br>point to point |
| Sample approach                | Fast home, retract, and advance movement<br>Automatic step-by-step approach  |

# **CX** Controller specifications

| High resolution<br>outputs (DAC)        | 12x 28 bit, 1 MHz/sampling; thereof 4x user<br>DAC, ±10V/3dB@200kHz  |
|---|--|
| ast outputs (DAC)                       | 4x 16 bit, 100 MHz/sampling; thereof 1x user<br>DAC, ±1V/3dB@10MHz   |
| High resolution<br>nputs (ADC)          | 10x 20 bit, 1 MHz/sampling; thereof 4x user ADC, ±10V/3dB@200kHz   |
| ast inputs (ADC)                        | 3x 16 bit, 100 MHz/sampling; thereof 1x user<br>ADC, ±1V/3dB@10MHz   |
| Signal analyzers                        | 2 signal analyzer function blocks that can be configured as dual channel lock-in   |
| PGA module<br>and embedded<br>processor | System-on-chip module with low-latency FPGA signal processing at 100MHz and dual-core ARM processor, 2GB RAM, 1.5GHz clock |
| Scan control                            | 28Bit X/Y/Z-DAC with ±10V/3dB@200kHz   |
| Detector inputs                         | Deflection/lateral signals each 16<br>bit/3dB@10MHz and 28 bit/3dB@200kHz  |
| Digital sync, Spike-<br>Guard           | 2-bit line/frame sync out 5 V/TTL galvanically isolated, Spike-Guard input   |
| Clock sync                              | 10MHz/3V clock input to synchronize data acquisition and processing  |
| Communication<br>to PC                  | Gigabit Ethernet, galvanically isolated  |



# Scanner specifications

| Scan head type  | Tip scanner                             |
|---|---|
| Maximum XY scan range                                   | 100 μm <sup>(1)</sup>                   |
| Maximum Z-range   | 10 µm <sup>(1)</sup>                    |
| XY linearity mean error                                 | < 0.1%                                  |
| XY flatness at max. scan range                          | typ. < 5 nm                             |
| Z-sensor noise level (RMS)                              | typ. 150 pm / max. 200 pm               |
| Z-measurement noise level<br>(RMS, static mode in air)  | typ. 100 pm / max. 200 pm               |
| Z-measurement noise level<br>(RMS, dynamic mode in air) | typ. 25 pm / max. 35 pm                 |
| Optical detection light source                          | 850 nm low coherence SLD                |
| DC detector noise                                       | <10 pm RMS (0.1Hz to 1kHz)              |
| AC detector noise                                       | <60 fm Hz <sup>-1/2</sup> above 100 kHz |
| Detector bandwidth                                      | DC to 4 MHz                             |

(1) Manufacturing tolerances ±10%

# Stage specifications

| Top view field of view   | 5 MP, 1.5 mm x 1.1 mm   |
|--|---|
| Side view field of view  | 5 MP, 3.2 mm x 3.2 mm   |
| Max. sample size   | 300 mm x 300 mm x 45 mm   |
| Max. sample weight   | 40 kg   |
| Vacuum chuck for   | 4" / 6"/ 8" / 12" wafers  |
| Motorized XY travel range  | 300 mm x 300 mm   |
| Motorized approach range   | 50 mm   |
| System dimensions  | 1008 mm x 1887 mm x 1208 mm<br>(fits through 800 mm door prior to<br>assembling the acoustic enclosure) |
| System weight  | 833 kg  |
|  |   |
| Stage XY resolution  | < 1 µm  |
| Stage XY resolution<br>Unilateral repositioning accuracy                       | < 1 µm<br>2 µm  |
| Stage XY resolution<br>Unilateral repositioning accuracy<br>Acoustic isolation | < 1 µm<br>2 µm<br>~30 dB above 250 Hz   |

# 🔭 nanosurf

Nanosurf AG Liestal, Switzerland +41 61 927 47 47

Nanosurf GmbH Langen, Germany +49 6103 202 7163

**Nanosurf UK** Bracknell, UK +44 1344 388 008

Nanosurf Inc. Woburn, MA, USA

+1 781 549 7361 Santa Barbara, CA, US +1 805 696 3938

Nanosurf 中国 Nanosurf China, Shanghai

上海市天宝路578号 (200086) +86 18621896399

Nanosurf India New Delhi, India +91 92 0552 0378

**Nanosurf Singapore** 574827 Singapore +65 9839 9938

info@nanosurf.com www.nanosurf.com Nanosurf and the Nanosurf Logo are trademarks of Nanosurf AG Copyright © 2019 Nanosurf AG, Switzerland

